

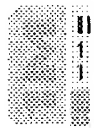
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1	BRS	L1	2	5238354.pn. 5870488.pn.	USPAT	2004/09/24 12:43		0
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3	BRS	L3	37140	mark\$ near (identif\$ locat\$ verif\$ read scan\$)	USPAT; US-PGPUB	2004/09/24 13:05		0
4	BRS	L4	2248	2 same 3	USPAT; US-PGPUB	2004/09/24 13:09		0
5	BRS	L5	17043 5	2 same (rotat\$ turn\$)	USPAT; US-PGPUB	2004/09/24 13:09		0
6	BRS	L6	243	5 same 3	USPAT; US-PGPUB	2004/09/24 13:40		0
7	BRS	L7	38	6 same (ccd camera scanner (scanning adj device) detecttor (photo adj detector) photodetector)	USPAT; US-PGPUB	2004/09/24 13:47		0
8	BRS	L8	13175	(calculat\$ correct\$) near (motion rotat\$)	USPAT; US-PGPUB	2004/09/24 13:47		0
9	BRS	L9	34	6 and 8	USPAT; US-PGPUB	2004/09/24 13:47		0
10	BRS	L10	24	9 and (ccd camera scanner (scanning adj device) detecttor (photo adj detector) photodetector)	USPAT; US-PGPUB	2004/09/24 13:47		0

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[\[Abstract\]](#)[\[PDF Full-Text \(172 KB\)\]](#)**IEEE JNL****3 Improvement in reading precision of micro-ID engraved on wafer***Uchida, I.; Suzuki, N.; Arikado, T.; Saitoh, Y.; Fujimoto, K.; Nakajima, K.;*

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